

MULTI-WAFER SCRUBBING DEVICE

ABSTRACT

Disclosed in the present invention is a multi-wafer scrubbing device, comprising a box body. Multiple compartments are provided in the box body; the bottoms of the multiple compartments are connected; a support wheel system and a scrubbing system are provided inside each compartment; the scrubbing system comprises a group of roller brush units; the roller brush units can get close to each other to scrub wafers or away from each other to take out the wafers; multiple scrubbing systems are connected by means of an opening and closing drive mechanism; the opening and closing drive mechanism is used for simultaneously driving multiple groups of roller brush units to get close to or away from each other. In the present invention, multiple groups of roller brush units are integrated into a same box body, thereby greatly shortening the distance between stations and effectively improving production efficiency per unit volume; the box body may have two compartments, three compartments or four compartments, etc., so the quantity of the compartments is highly customized and the range of application is wide; by sharing one opening and closing drive mechanism, different roller brush units can be opened or closed synchronously, thereby saving device space and reducing procurement costs.

FIG. 1